



SW Test Workshop
Semiconductor Wafer Test Workshop

**High Voltage, High Temperature,
High Current...
...and sometimes all come together
at the same time!**

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Overview

- **High Power Devices - Challenges for Wafer Test**
- **...some Physics**
- **High Voltage + High Temperature: "Why's that?"**
- **Lab Test: Full Wafer HV – HT contactor**
- **Production Test: SiC, GaN and more...**
- **"Hot-Cold Air Stream" High Voltage Probe Card**

High Voltage on Wafer – Challenges

- **HV Flashovers**
 - If test voltage exceeds insulation strength of atmosphere:
- **known as "arcing", "sparks", "flashovers"**
 - can have unwanted effects for the device under test ...

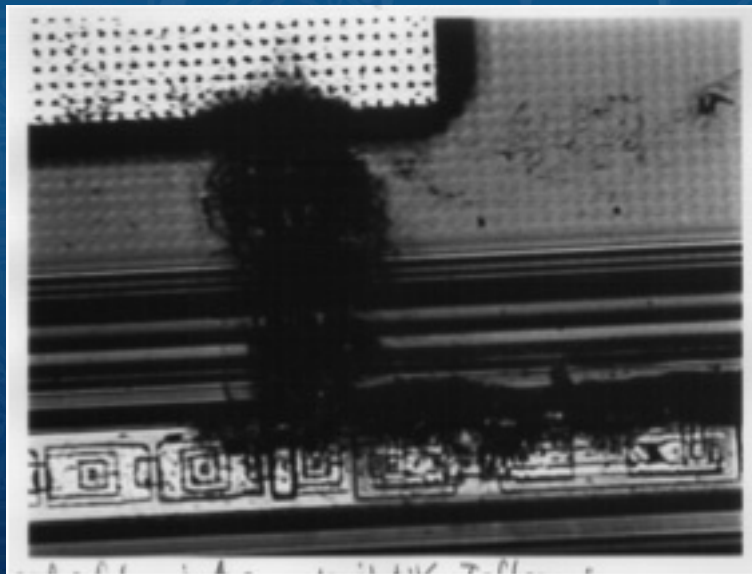
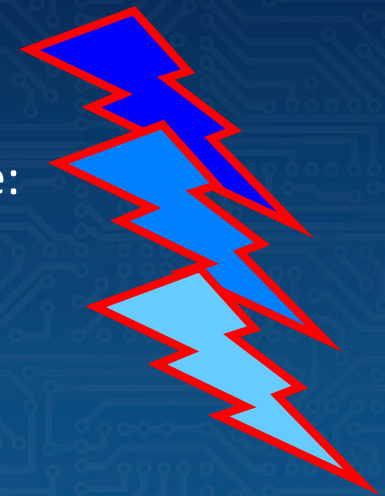


Fig. 1:
Damage on
wafer
surface
(IGBT) due
to flashover
between
source-pad
and dicing
frame
structure

High Voltage – some Physics...

- Flashover Mechanism: Avalanche Ionization of Gas Molecules, "Arc Discharge"

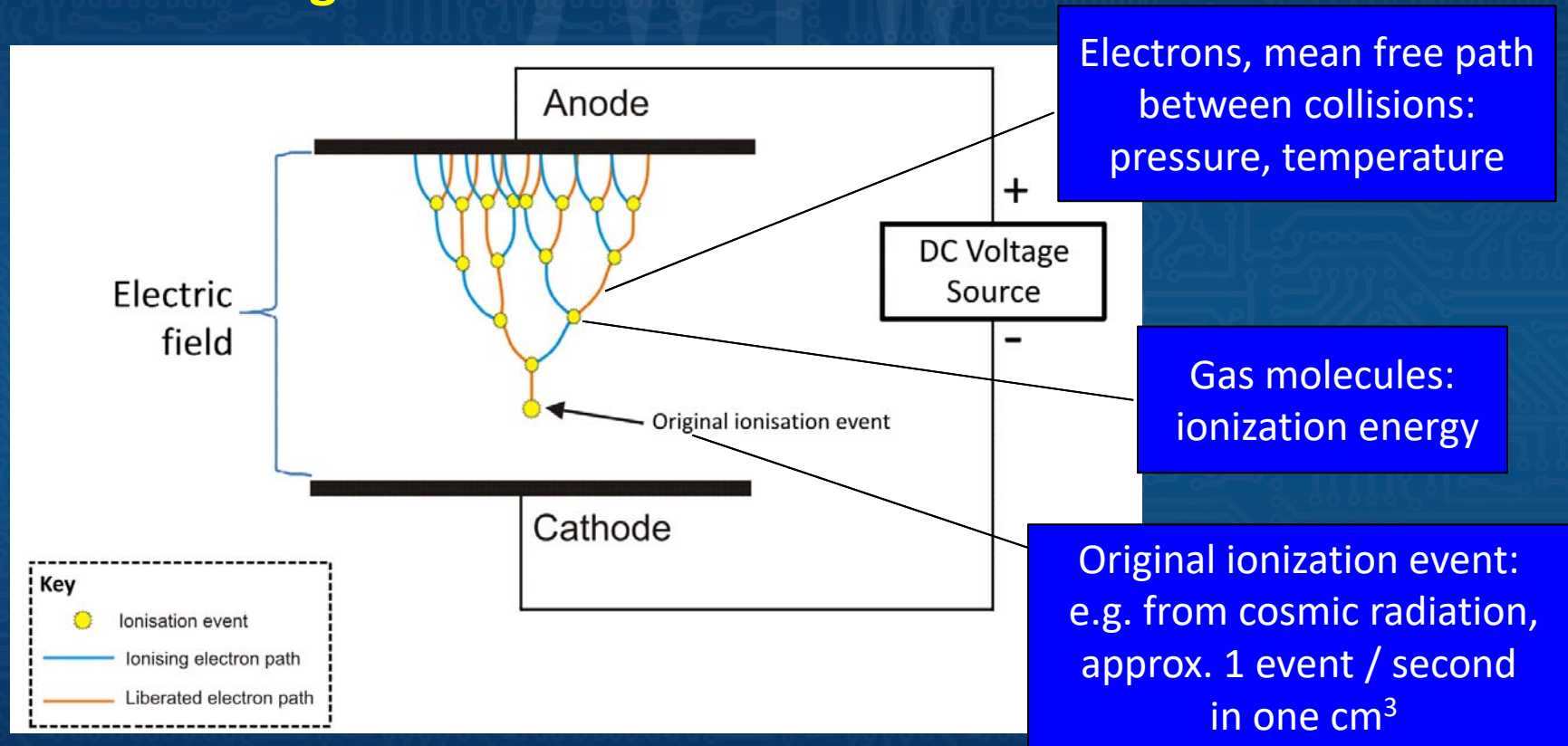


Fig. 2: Visualisation of a Townsend Avalanche *)

*) picture source: Wikipedia

...more Physics !

- **Physics of "Gas Discharges"**

- first described by Friedrich Paschen in his PhD thesis in 1889: ¹⁾

- "Breakdown voltage between two electrodes in a gas is a function of gap distance and pressure" (Paschen's law).

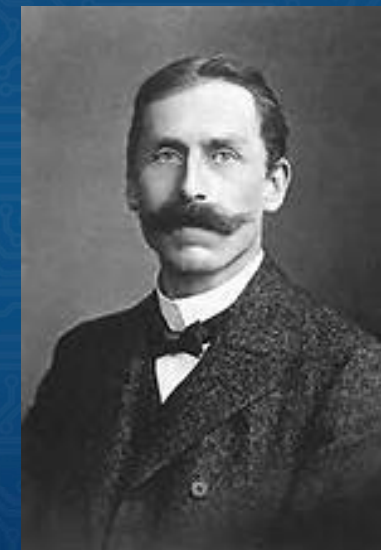
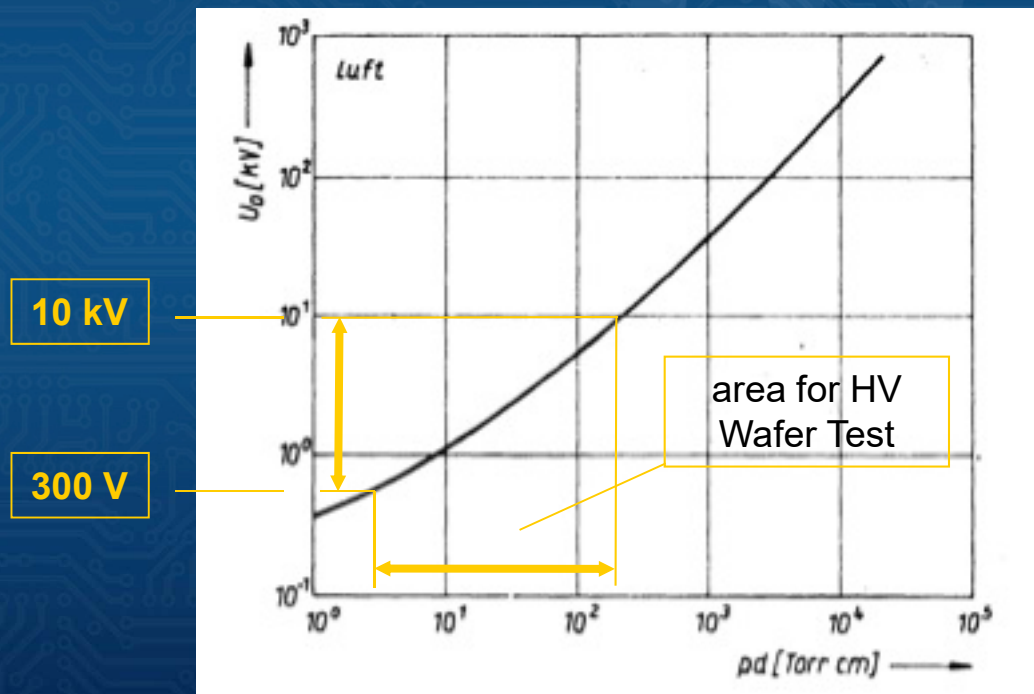


Fig. 3:
Paschen
Curve for
air ²⁾

Friedrich Paschen ^{*)}

^{*)} picture source: Wikipedia

High Voltage and Temperature...

- **Ideal Gas: Molecule density is temperature dependent**
 - the higher the temperature, the lower the molecule density - and the higher the mean-free path for a given pressure e.g. atmospheric pressure
 - increased mean-free-path length leads to lower flashover voltage
 - mathematical description by the "Ideal Gas Law": $p V = n R T$
- **Thus: Increasing pressure -> increased arcing voltage**
- **Increasing temperature -> decreasing arcing voltage**
 - rules of thumb:
 - *Doubling (absolute) pressure will double arcing voltage .*
 - *Increasing test temperature from room temperature 23 °C to 150 °C will decrease arcing voltage by 33 % - or require pressure increased by 50 % (absolute) to compensate for.*

Case 1: Hot Temp and High Voltage Lab Test... "Why's that?"

- **Characterization of Temperature Dependence of Avalanche Breakdown in IGBT Termination Structures**
 - needed during development of "VLD (variation of lateral doping) termination structure" – Infineon Technologies

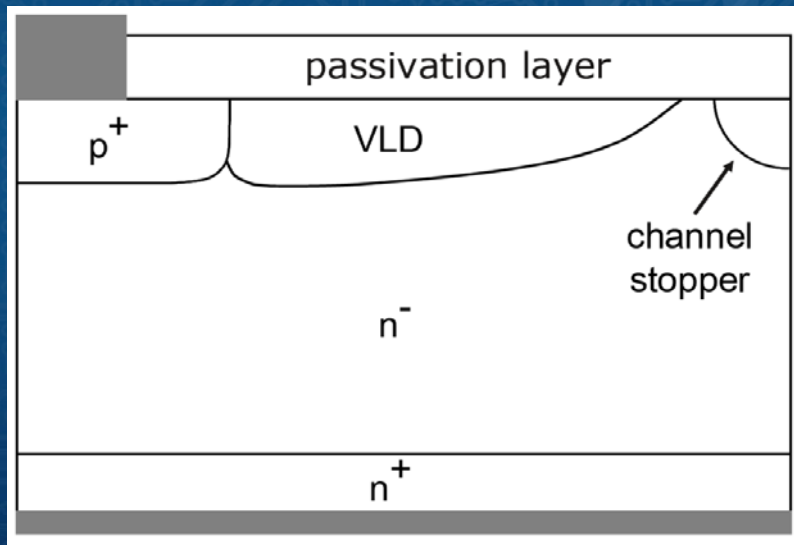


Fig. 4: Schematic cross section of VLD termination structure ³⁾

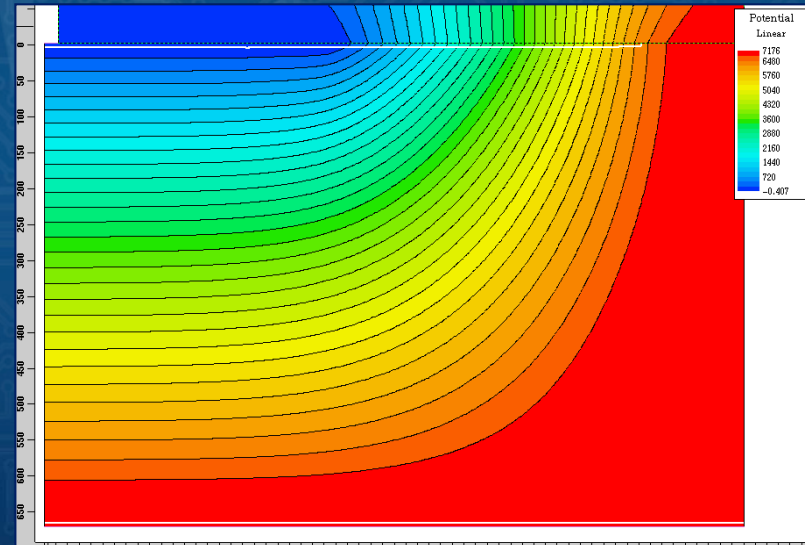


Fig. 5: Simulation of electric field in termination structure at U = 7200 V

New chip design - HV verification

- Measurement task: HV blocking capabilities of different chip design versions over temperature

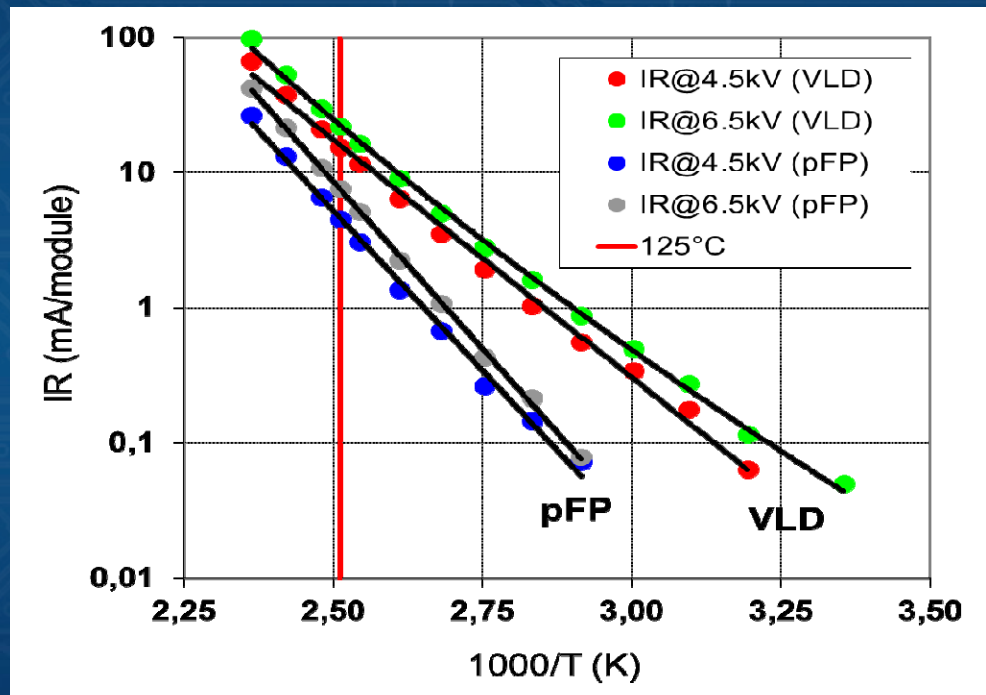
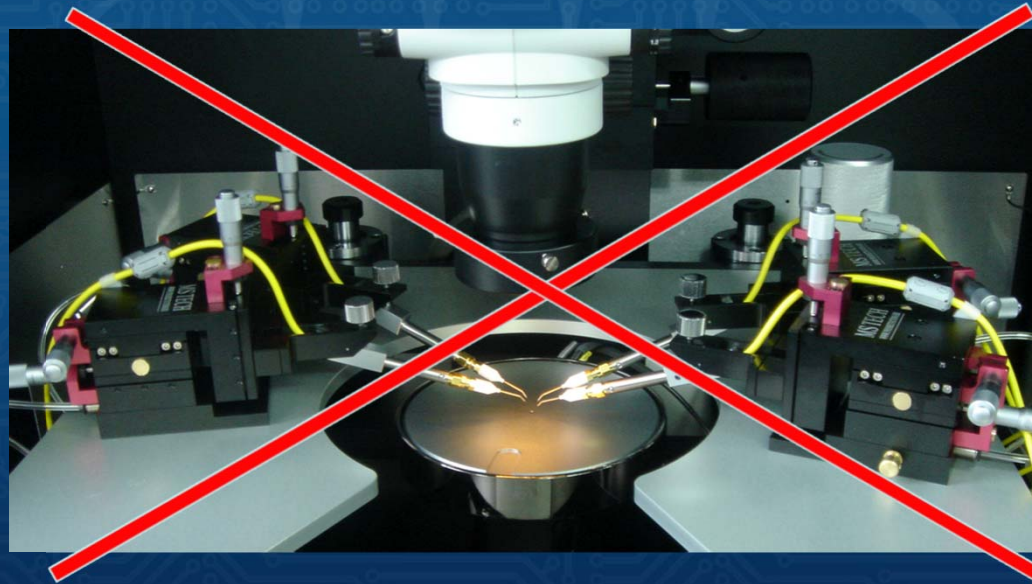


Fig. 6: Leakage current for IGBTs with different termination structures as a function of temperature ³⁾

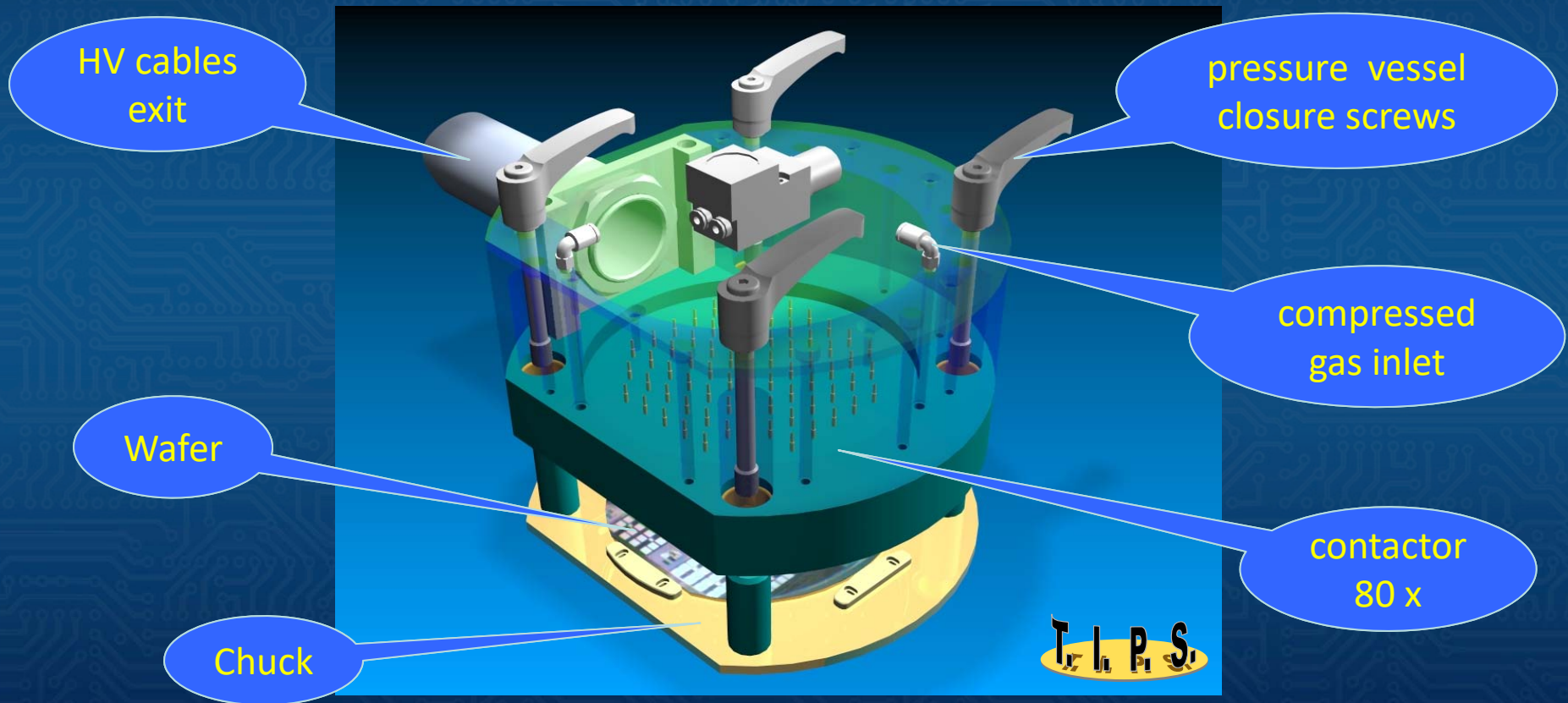
HV chip design verification

- **High numbers of measurements to be done for good statistical significance**
 - "Classic" laboratory characterization approach with manipulator probes is extremely time consuming due to complicated chip preparation required – wouldn't meet timelines requested...



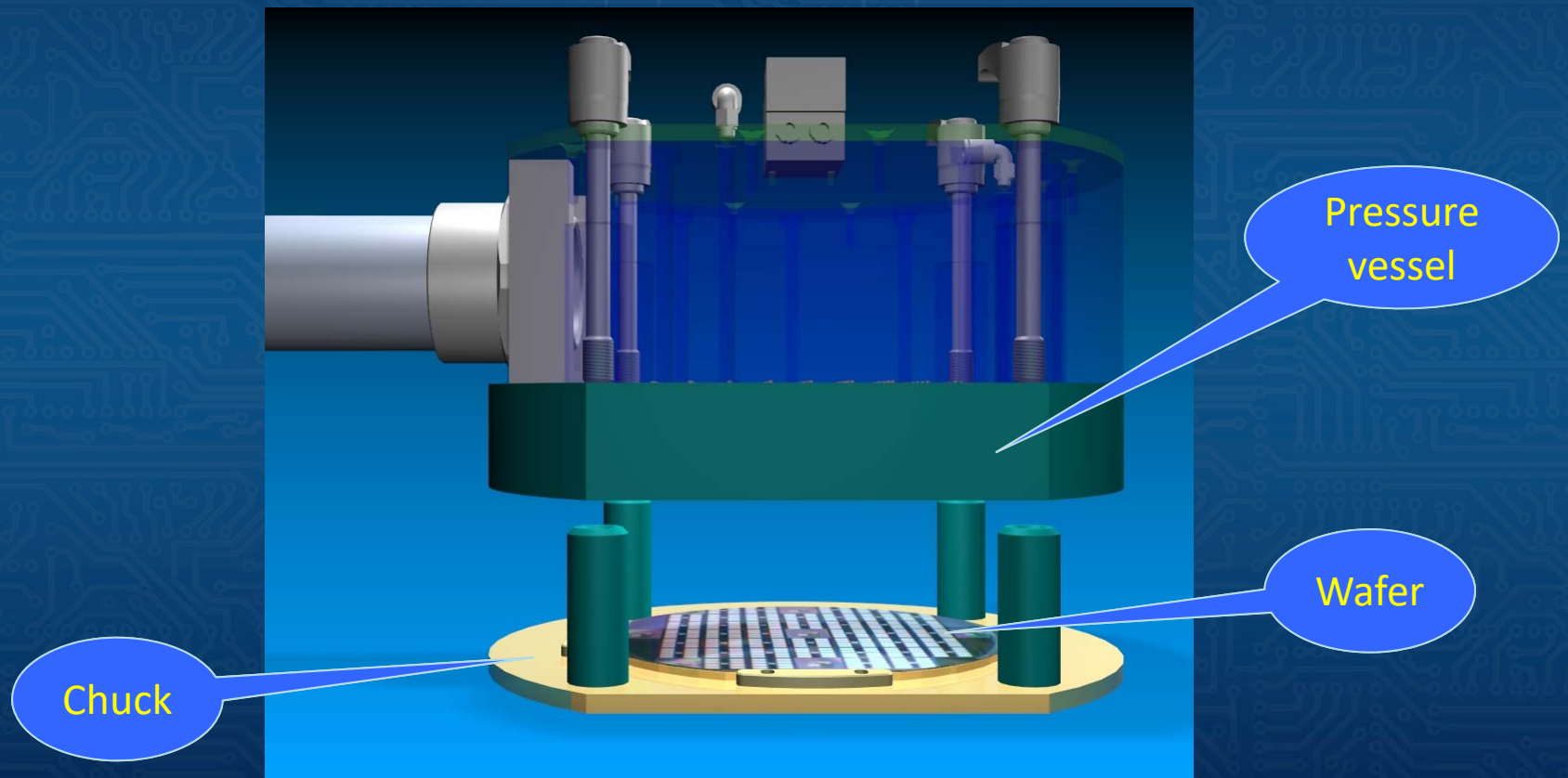
HV Full Wafer Contactor

- 6" full wafer wafer single touchdown, 80 x parallel test, 10 kV capable, - 40 °C - 175 °C, max. 4 bar pressure vessel



HV Full Wafer Contactor (2)

- "non-gas-loss" design: instead of compressed air also use of compressed HV insulating gas (SF6) is possible



"HV – Messplatz, Villach"



Dr. Gerhard
Schmidt

HV enclosure
cabinet

HV
full wafer
contactor

Summary – Lab Test Setup

- **6" full wafer contactor allows fast high voltage characterization of HV IGBT and diodes and greatly speeds up development for new HV chip designs.**
- **Full temperature range coverage from – 40 °C – 175 °C,**
- **lossless pressure vessel allows (restricted) use of insulating gases (e.g. SF6) for most demanding applications**
- **Very low parasitic current leakage (1 nA @ 10 kV)**

Case 2: Production Wafer Sort

- **Device under test: one of the "exotic" SiC, GaN... specimens**
- **900 V – 20 A – 175 °C – and very narrow HV structures**
 - First proposal: use off-the-shelf TIPS High Voltage "LuPo" probe card with floating air bearing seal, supplied with compressed air at ambient temperature, hot chuck

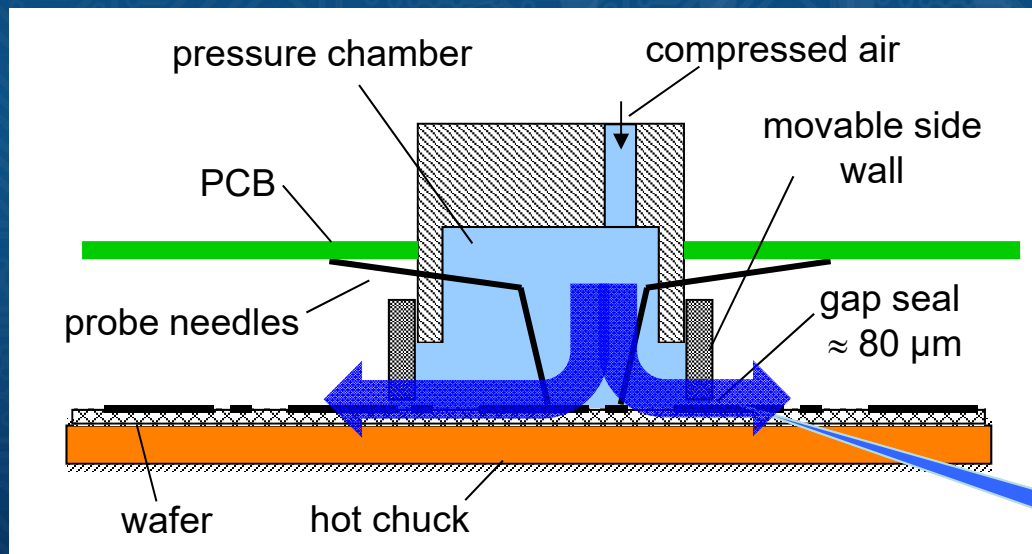


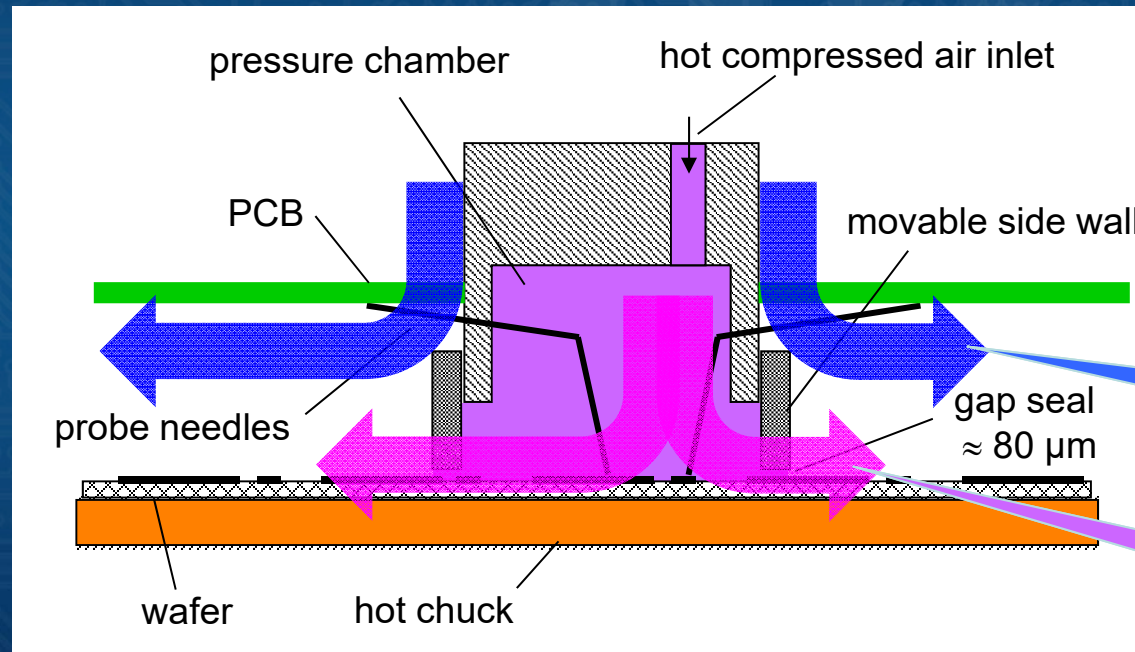
Fig. 7: Schematics of compressed air "LuPo" probe card

- Air flow causes sharp temperature drop at DUT location
- Thermo-Chuck temperature control "dances polka" when facing local chuck cooling.

cool air flow

Hot-Cold-Airstream Probe Card

- compressed hot air at chuck temperature to create hot compressed air test environment
- cold air stream to insulate probe card components from heat



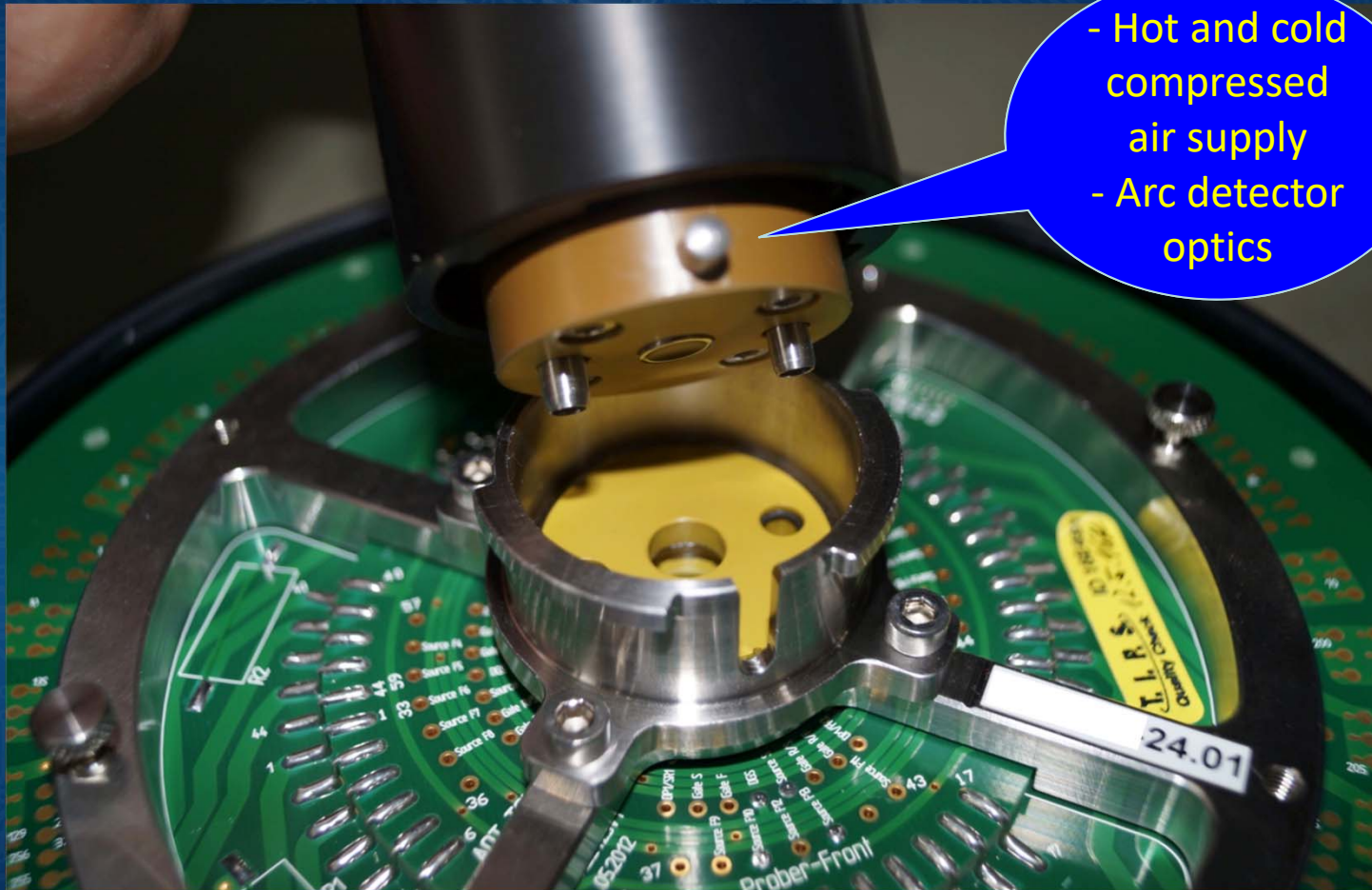
FEM computation used to "tune" thermal gradients during probe card mechanical design

cold air flow

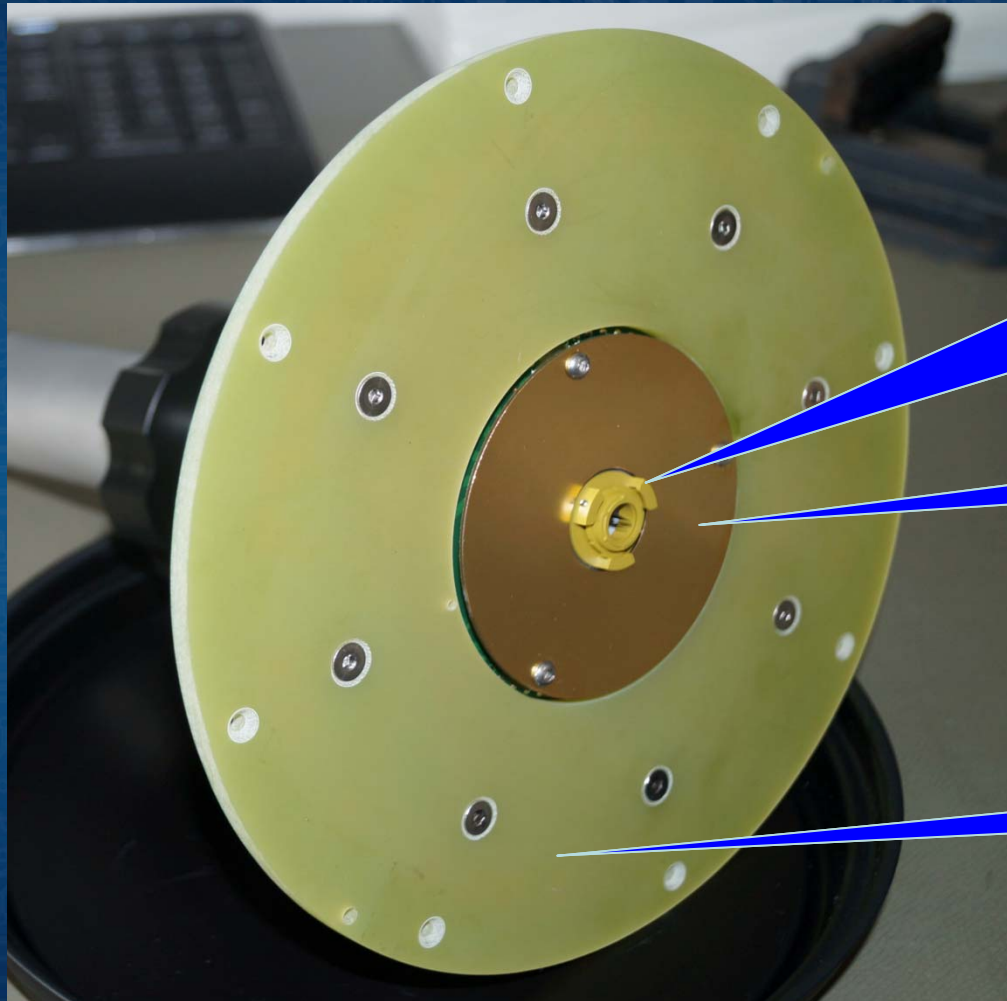
hot air flow

Fig. 8: Schematics of Hot-Cold-Airstream "LuPo" probe card

Hot-Cold-Airstream Probe Card (2)



Hot-Cold-Airstream Probe Card (3)



Needle spider
with "LuPo G3"
pressure chamber

baffle

Probe card
PCB -
bottom

Conclusion

- High Voltage – High Current – High Temperature wafer probing is feasible – but with "hard constraints" imposed by physics
- For production test: It's like having a hot air gun inside your prober – So if you can avoid it...
- If you can't avoid it...
....at least be careful not to burn your fingers! 😊

Thank you for your attention!

Acknowledgements

- unnamed customers willing to try out new things...
- our design and manufacturing team at T.I.P.S.

References

- 1) **"Ueber die zum Funkenübergang in Luft, Wasserstoff und Kohlensäure bei verschiedenen Drucken erforderliche Potentialdifferenz"**, F. Paschen, Annalen der Physik, vol. 273, no. 5, pp. 69 – 96, 1889
- 2) **Der elektrische Durchschlag in Gasen**, H.Hess, Vieweg Verlag 1976, ISBN 3528068183 9783528068189
- 3) **6.5kV IGBT and FWD with Trench and VLD Technology for reduced Losses and high dynamic Ruggedness**, Thomas Duetemeyer¹), Josef-Georg Bauer²), Elmar Falck²), Carsten Schaeffer³), G. Schmidt³), Burkhard Stemmer¹), PCIM Europe 2008 Conference Proceedings, ISBN: 978-3-89838-605-0